



MEMSIC Introduces METF2000 Series of MEMS Gas Mass Flow Meters for Industrial Applications

ANDOVER, Mass., Nov. 22, 2010 (GLOBE NEWSWIRE) -- MEMSIC, Inc. (Nasdaq:MEMS), a leading innovator of MEMS sensors and systems solutions, today announced its first generation family of high-performance MEMS Gas Mass Flow Meters. The METF2000 is the first release in this new series of gas mass flow meter products that challenge the price and performance of traditional gas flow meters.

The METF2000 Gas Mass Flow Meter is based on patented thermal MEMS technology and directly senses the gas mass flow, without the need for temperature or pressure compensation. With a user-friendly operational interface and standards-based remote communication protocol, it is ideally suited for a variety of gas process control applications.

"The METF2000's wide dynamic range and high sensitivity enables customers to measure extremely low gas mass flow rates more accurately and cost-effectively than traditional meter solutions," said Steve Tsui, Vice President of Worldwide Sales - System Business. "It creates exciting opportunities for our customers to upgrade their flow metering systems for energy saving, process optimization, and other value-added advancements."

The METF2000 series of MEMS Gas Mass Flow Meters is designed to serve the needs of a wide range of industries, including steel, chemical, food, beverage, natural gas network. Key features of the METF2000 include: large turn-down rate (> 100:1), extremely low flow sensitivity (<2 mm/s), direct mass flow sensing, immunity to vibration, and less straight-run requirement.

The METF2000 Gas Mass Flow Meter is now available, and pricing inquiries may be directed to flowsales@memsic.cn.

About MEMSIC, Inc.

MEMSIC Inc., headquartered in Andover, Massachusetts, provides advanced semiconductor sensor and system solutions based on integrated micro-electromechanical systems (MEMS) technology and mixed signal circuit design. MEMSIC's unique and proprietary approach combines leading edge sensor technologies, such as magnetic sensors and accelerometers, with mixed signal processing circuitry to produce reliable, high quality, cost effective solutions for automotive, consumer and industrial markets. The company is listed on the NASDAQ Stock Exchange (Nasdaq:MEMS).

Safe Harbor Statement

Statements included in this press release that are not historical in nature are forward-looking statements made pursuant to the safe harbor provisions of the Private Securities Litigation Reform Act of 1995. Such statements are based upon the current beliefs and expectations of the company's management and are subject to significant risks and uncertainties. Actual results may differ materially from those set forth in the forward-looking statements for reasons identified under the heading "Risk Factors" in the company's most recent annual report on Form 10-K and other periodic reports filed with the Securities and Exchange Commission. The forward-looking statements contained in this press release are made as of the date hereof, and the company does not undertake any obligation to update any forward-looking statements, whether as a result of future events, new information or otherwise.

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